

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Continuation of Daniel J.C. Herr et al;

Application No. not yet assigned

Filed: currently herewith

For: PATTERNING METHODS AND SYSTEMS USING REFLECTED
INTERFERENCE PATTERNS

Date: March 9, 2004

Mail Stop PATENT APPLICATION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

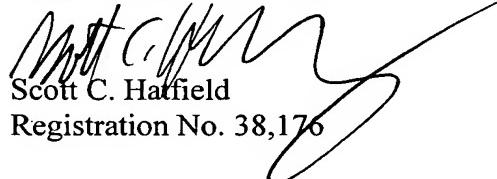
INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a list of documents on form PTO-1449. Items 1-34 listed on the PTO-1449 were cited in parent application Serial No. 09/781,881, filed February 12, 2001. As the benefit of this application is claimed under 35 U.S.C. §120, no copies need to be furnished in accordance with 37 C.F.R. §1.98(d); however, copies will be furnished on request. It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 C.F.R. §1.56 and Section 609 of the MPEP.

No fee is believed due. However, the Commissioner is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-0220.

Respectfully submitted,


Scott C. Hatfield
Registration No. 38,176

Myers Bigel Sibley & Sajovec, P.A.
P. O. Box 37428
Raleigh, North Carolina 27627
Telephone: (919) 854-1400
Facsimile: (919) 854-1401
Customer No. 20792

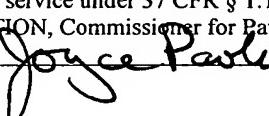
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Joyce Paoli



Substitute form 1449A/PTO				<i>Complete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	not yet assigned
				Filing Date	concurrently herewith
				First Named Inventor	Daniel J.C. Herr
				Group Art Unit	
				Examiner Name	
Sheet	1	of	2	Attorney Docket Number	5347-204CT

U.S. PATENTS AND PATENT PUBLICATIONS					
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
	1	US-3,582,176		Mathisen	06/1971
	2.	US-4,325,637		Moore	04/1982
	3.	US-4,498,771		Makosch et al;	02/1985
	4.	US-4,614,427		Koizumi et al;	09/1986
	5.	US-5,568,256		Koener et al;	10/1996
	6.	US-5,923,423		Sawatari et al;	07/1999
	7.	US-5,455,850		Howells et al;	10/1995
	8.	US-5,973,807		Buchkremer et al;	10/1999
		US-			
		US-			
		US-			

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No.	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Office	Number	Kind Code (if known)	
	9.		11-329944		JPO (Abstract in English) 11/1999
	10.		2221353		Great Britain 01/1990
	11.		06-283585		Japan 10/1994
	12.		03-295408		Japan 12/1991
	13.		09-016062		Japan (Abstracts) 01/1997

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 2 of 2

Complete if Known

Application Number

Filing Date

First Named Inventor

Group Art Unit

Examiner Name

Attorney Docket Number

OTHER NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
	14.	V. Georges et al; <i>Images charged objects using low-energy-electron coherent beams</i> , Ultramicroscopy 90 (2001) pp 32-38.	
	15.	Palmer et al., "Diffraction gratings," Rep. Prog. Phys., Vol. 38, 1975, pp. 975-1048	
	16.	Microchannel Plate (MCP), http://www.hpk.co.jp/eng/products/ETD/mcpe/mcpe.htm , 3/28/03, 2 pages	
	17.	Microchannel Plate Principles of Operation, http://hea-www.harvard.edu/HRC/mcp/mcp.html , 3/28/03, 4 pages	
	18.	Skala, Melissa, "Imaging X-Ray Fluorescence Using Microchannel Plate (MCP) Optics, Physics Department, Washington State University, Pullman, WA 99163, no date, 10 pages	
	19.	A Well Collimated Quasi-Continuous Atom Laser, http://physics.nist.gov/Divisions/Div842/Gp4/AtomOptics/intro.html , 5/26/03, 2 pages	
	20.	Module 1-4 Properties of Light, http://www.dewtronics.com/tutorials/lasers/leot/course01_mod04/mod01-04.html , 5/26/03, 32 pages	
	21.	E. Hecht: "Optics" 1987, Addison-Wesley XP002184727, page 593-596	
	22.	Anonymous: "Wafer Conformable Mask Image", Research Disclosure (December 1984) page 609 XP002184726.	
	23.	C. Jacobsen et al; "Projection X-Ray Lithography Using Computer-Generated Holograms: A study of compatibility with proximity lithography"; Journal of Vacuum Science and Technology: Part B, Am Inst. of Physics. New York, US. vol. 10. No. 6 (11/1/1992) pgs 3177-3181 XP000332529	
	24.	C. Jacobsen et al; "X-Ray Holographic Microscopy Using Photoresists", Journal of the Optical Society of America – A, Optical Society of America, Wash. US. vol. 7, no 10 (10/1/1990) pgs 1847-1861 XP000163095.	
	25.	Elliott, "Integrated Circuit Manufacturing Technology", pp 76-81 (1982)	
	26.	Machine translation of Tetsuo et al., JP 11-329944	
	27.	Machine translation of Tetsuo et al., JP 06-283585	
	28.	J.C.H. Spence et al; <i>Low Energy Point Reflection Electron Microscopy</i> , Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587	
	29.	J.C.H. Spence et al; <i>On the reconstruction of low voltage point projection holograms; Electron Holography</i> , (1995) pp 267-276	
	30.	Hans-Werner Fink et al; <i>State of the Art Low-Energy Electron Holography</i> , Electron Holography (1995) pp 257-266	
	31.	J.C.H. Spence et al; <i>Electron Holography at Low Energy</i> , Introduction to Electron Holography, pp 311-331	
	32.	D.C. Joy et al; <i>Advanced SEM Imaging</i> , Characterization and Metrology fur ULSI Technology; 1998 International Conference, pp 653-666	
	33.	Russell Young et al; <i>The Topografiner: An Instrument for Measuring Surface Microtopography</i> , Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011	
	34.	G. Morton et al; <i>Point Projector Electron Microscope</i> , Phy. Rev. Vol. 56, 705 (1939)	

Examiner Signature		Date Considered	
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